



# **SiPM characterization at LAL**

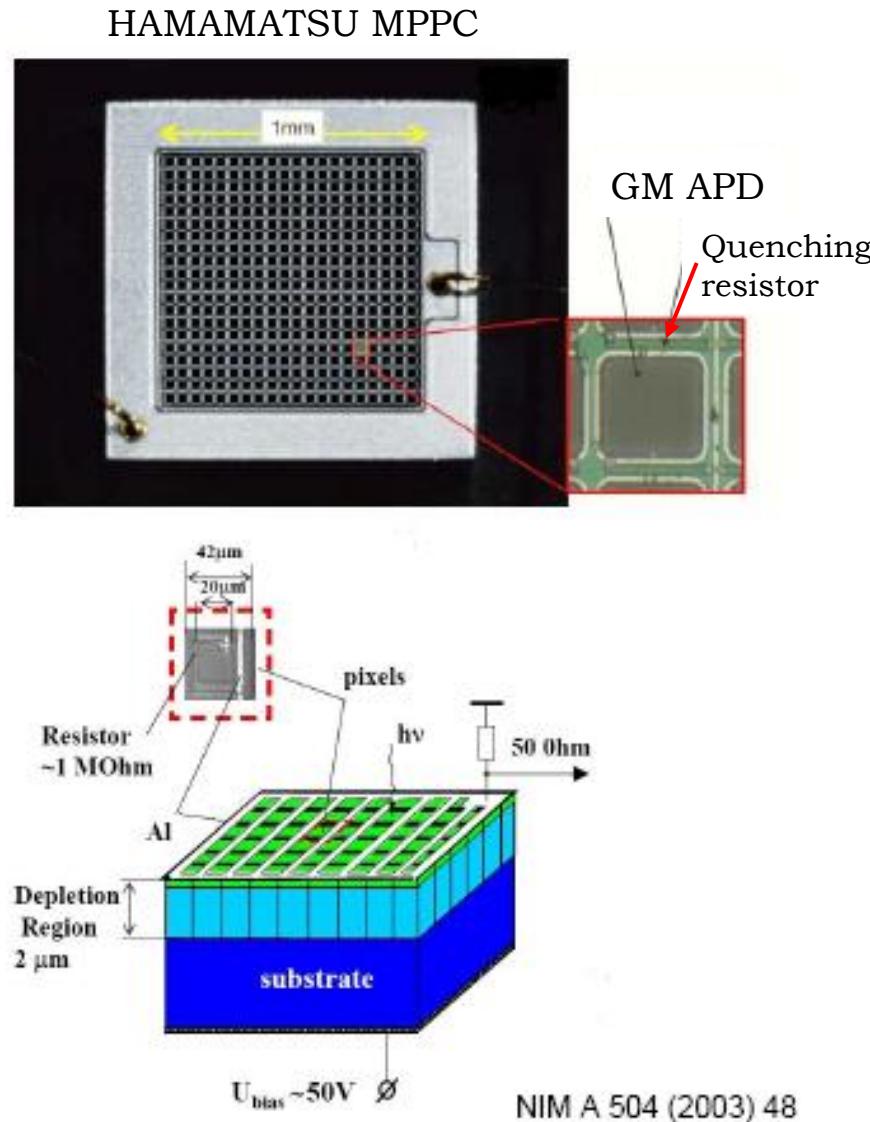
**XI SuperB Workshop  
Frascati, December 1-5 2009**

Véronique Puill

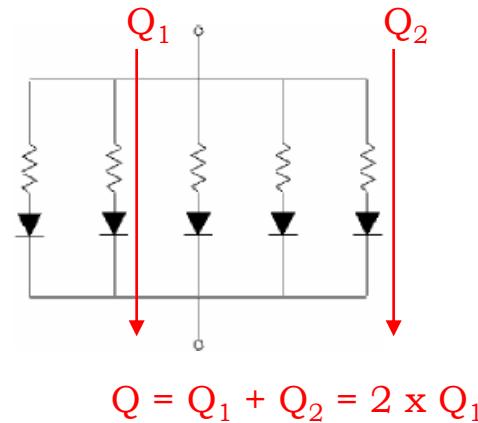
On behalf of the Instrumentation Group :

C. Bazin, V. Chaumat, N. Dinu, Jean-François Vagnucci,  
D.W. Kim (from December)

# The Silicon Photomultiplier (SiPM)



- Single SiPM segmented in micro GM-APD cells (pixels)
- Each pixel has one passive quenching resistor
- All pixels connected in parallel.



Output charge  $\alpha$  nb of triggered pixels  
 $\alpha$  nb of incident photons

# Characterization of SiPM at LAL

- ❖ Active area : geometrical parameters (fill factor)

- ❖ Operational voltage range

$\left. \begin{array}{l} \text{Breakdown voltage } (V_{BD}) \\ \text{Dark noise (DCR)} \end{array} \right\}$

- ❖ Noise : DCR + after-pulse + cross-talk

- ❖ Gain

- ❖ Dynamic range

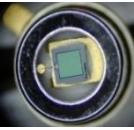
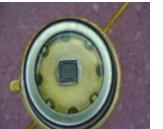
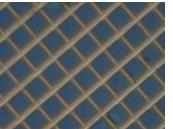
$\left. \begin{array}{l} \text{saturation} \\ \tau \text{ recovery} \end{array} \right\}$

- ❖ Photon Detection Efficiency (PDE)

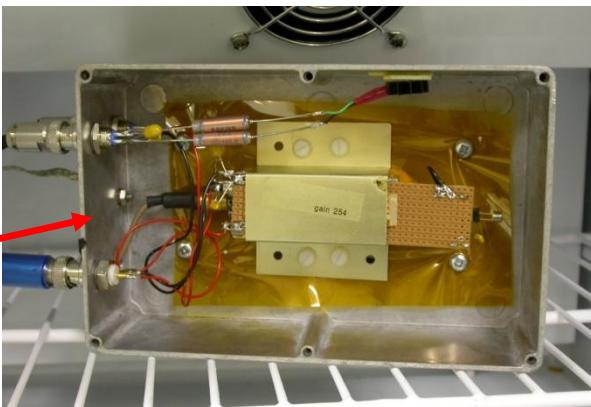
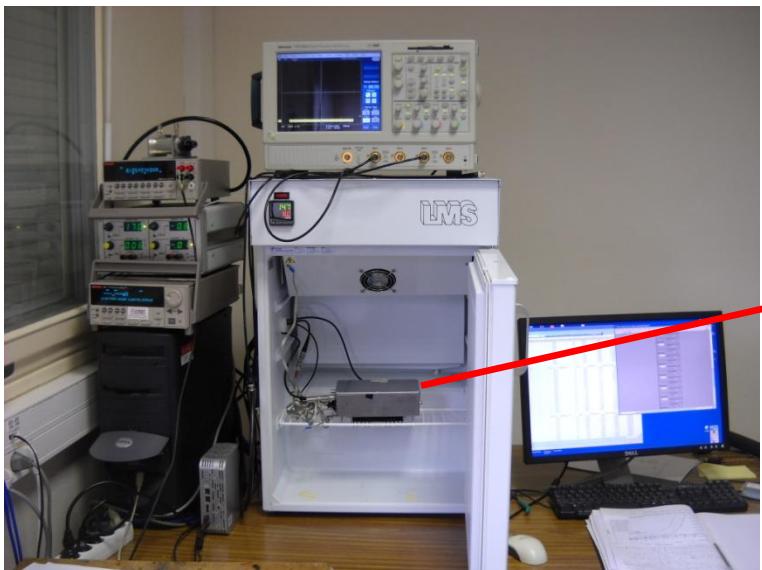
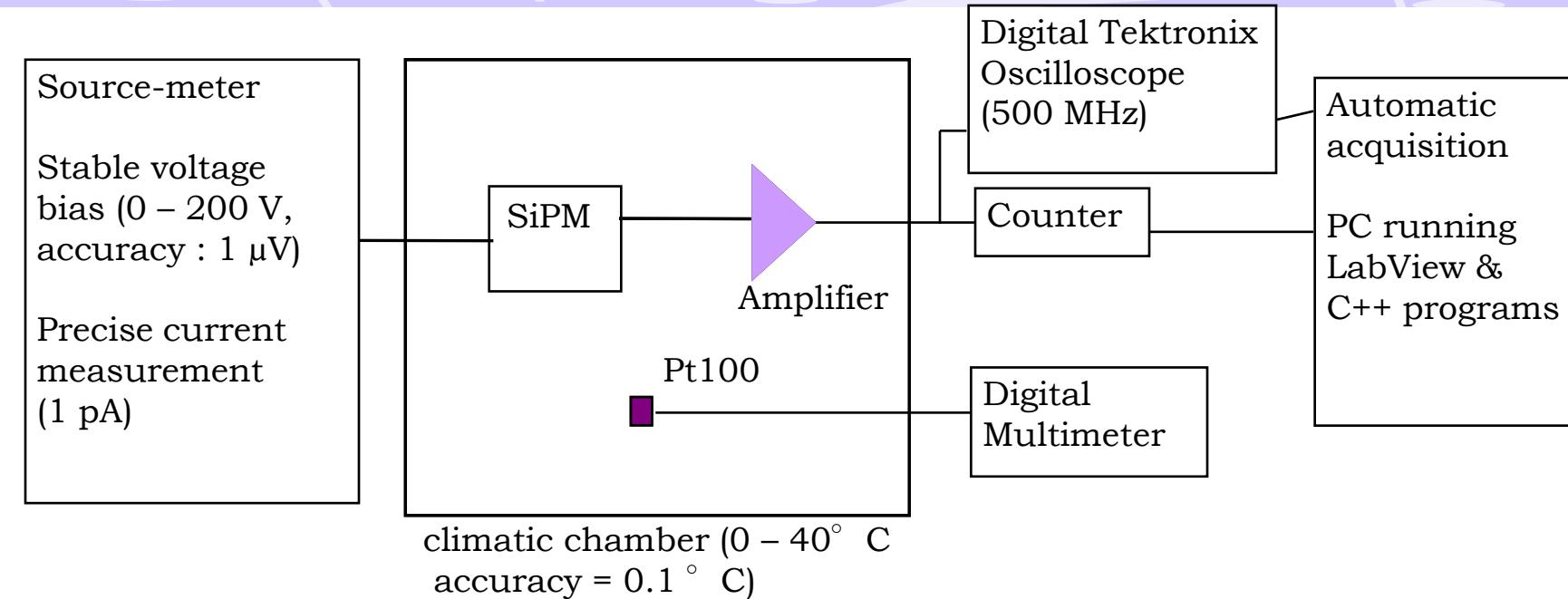
Optical Test Bench

DTM Test Bench

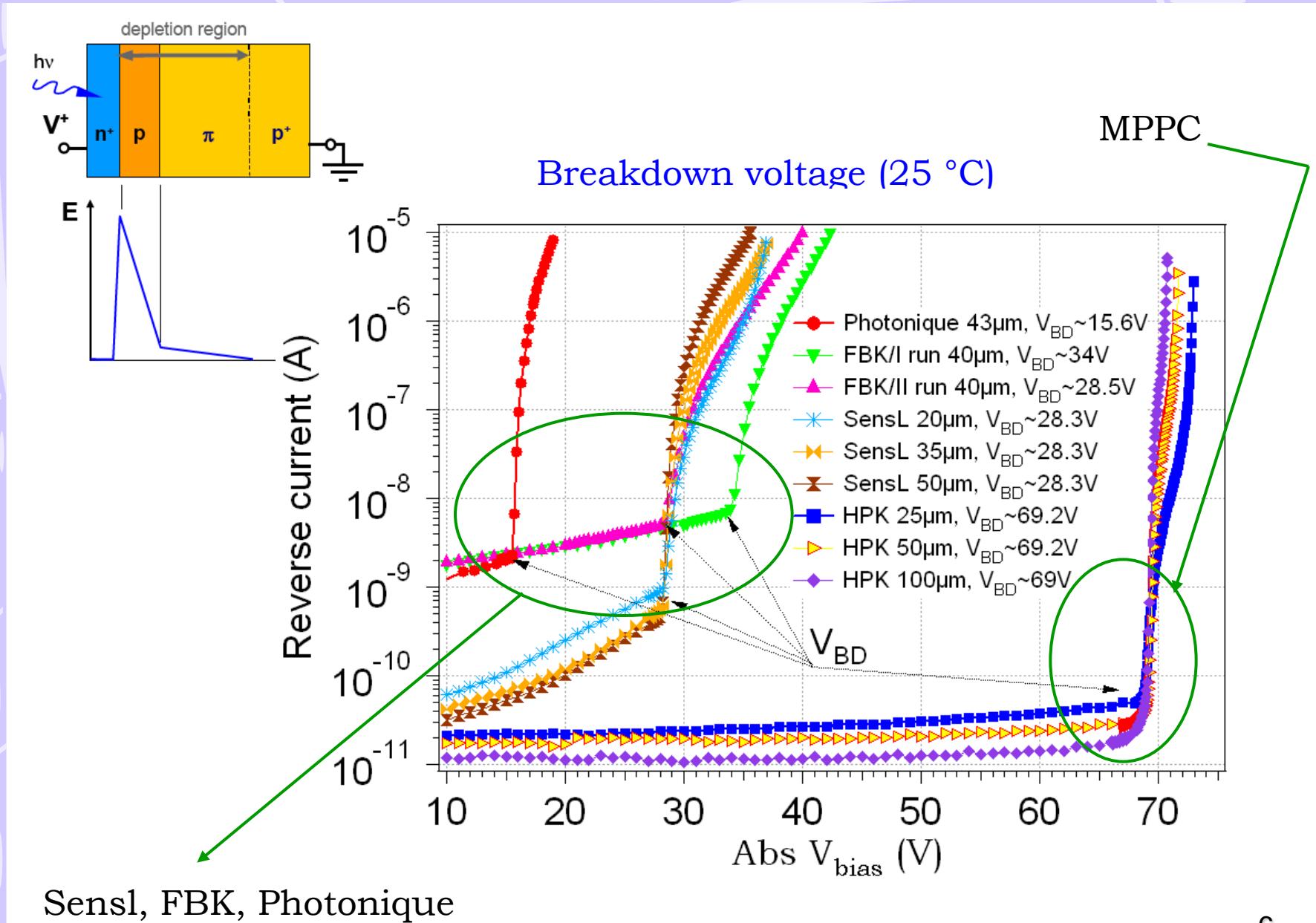
# SiPMs ( $1 \text{ mm}^2$ ) studied at LAL

	Reference	Pixel nb	Pixel size ( $\mu\text{m}$ )	Fill factor (%)
<b>F.B.K W</b>				
 	<b>W20-B10-T3V2PD</b>	<b>625</b>	<b>40 x 40</b>	<b>20</b>
	<b>W3-B3-T6V1PD</b>	<b>625</b>	<b>40 x 40</b>	<b>16</b>
<b>Hamamatsu MPPC</b>				
 	<b>S10362-11-25</b>	<b>1600</b>	<b>25 x 25</b>	<b>31</b>
	<b>S10362-11-50</b>	<b>400</b>	<b>50 x 50</b>	<b>61.6</b>
	<b>S10362-11-100</b>	<b>100</b>	<b>100x 100</b>	<b>78.5</b>
<b>SensL SPM</b>				
 	<b>SPM-20</b>	<b>848</b>	<b>29 x 32</b>	<b>43</b>
	<b>SPM-35</b>	<b>400</b>	<b>44 x 47</b>	<b>59</b>
	<b>SPM-50</b>	<b>216</b>	<b>59x 62</b>	<b>68</b>
<b>Photonique SSPM</b>				
 	<b>SSPM-0701-BG</b>	<b>556</b>	<b>43 x 43</b>	<b>70</b>

# Facility 1 : The Dark Monitored Temperature (DMT) Test Bench



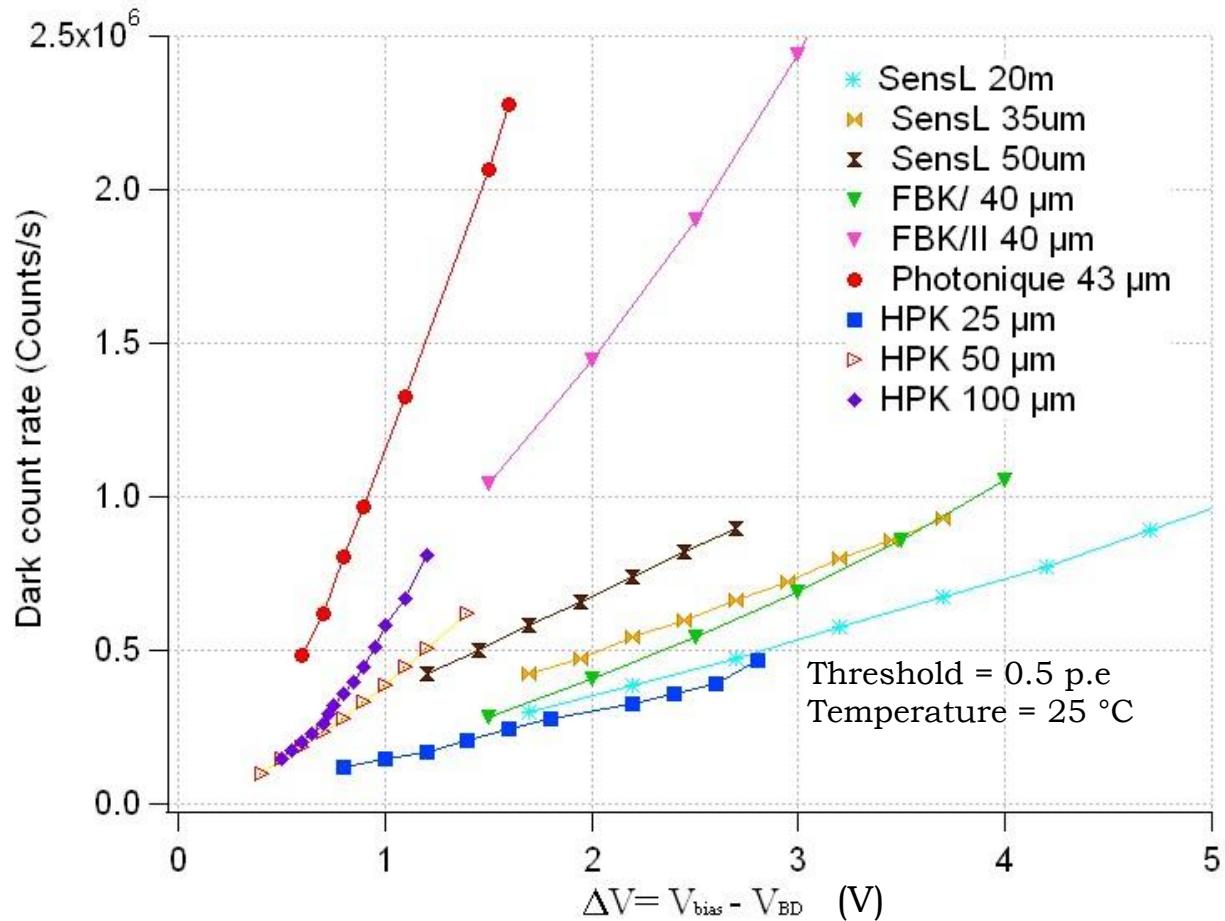
# Determination of the operational voltage range : phase 1 : $V_{BD}$



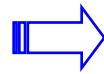
Sensl, FBK, Photonique

# Determination of the operational voltage range : phase 2 : DCR

Dark noise : thermally produced avalanches. Look the same as pulses from photon

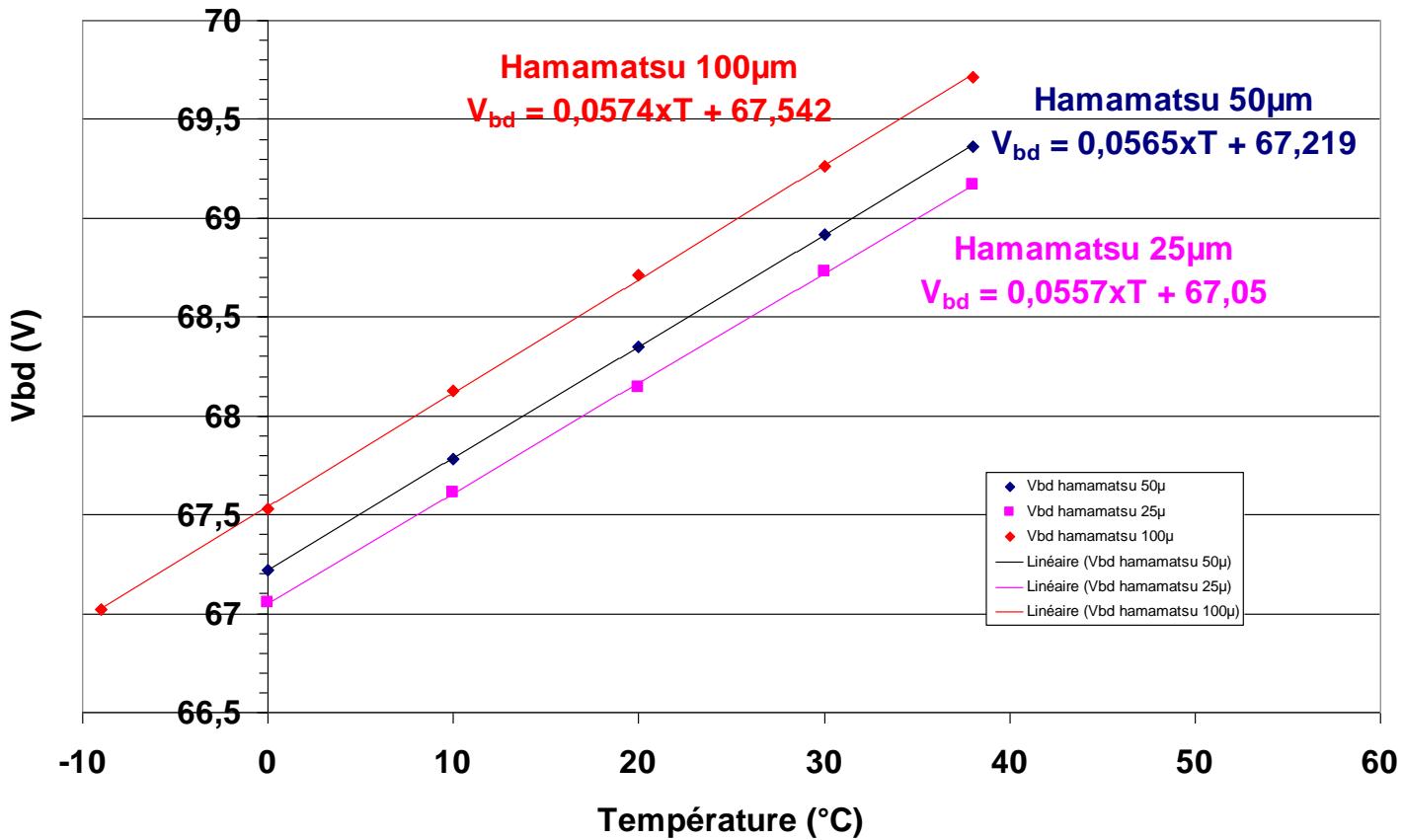


Operational voltage range :



$\Delta V/V_{BD} \sim 10\text{-}13\%$  for Photonique, FBK, SensL SiPM  
 $\Delta V/V_{BD} \sim 2\text{-}5\%$  for HAMAMATSU MPPC

# Evolution of V<sub>BD</sub> with temperature



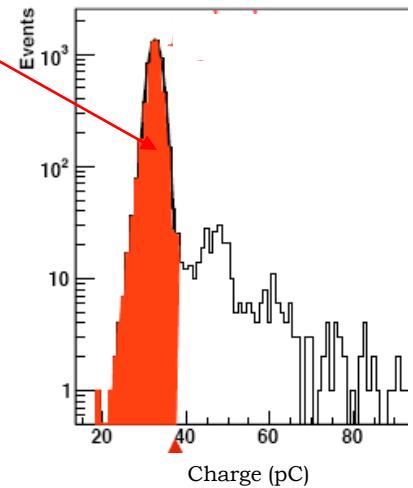
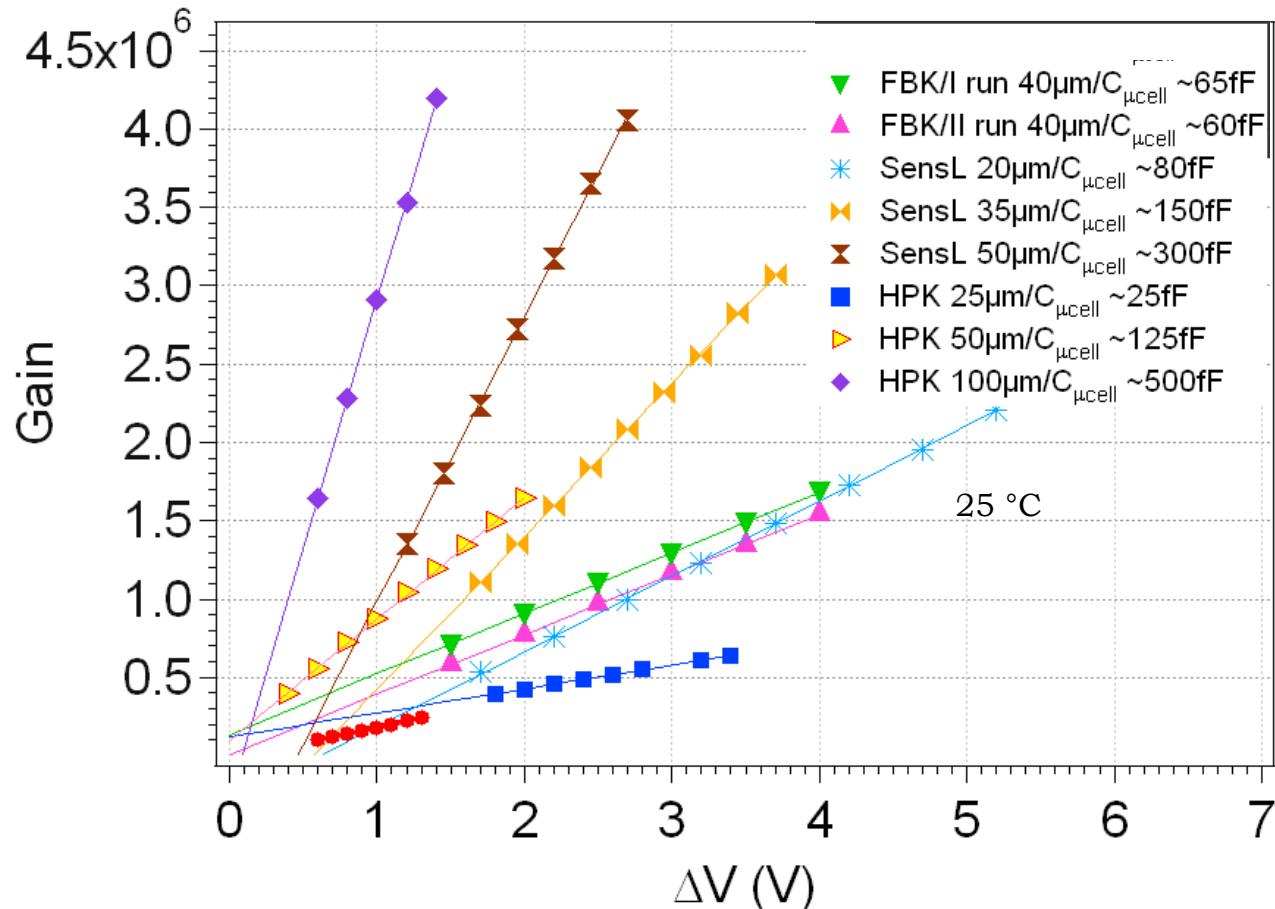
Breakdown voltage increases with the temperature

$$dV_{BD}/dT \sim 56 \text{ mV/}^{\circ}\text{C}$$

# Gain

Defined as the charge developed in one pixel by a primary carrier

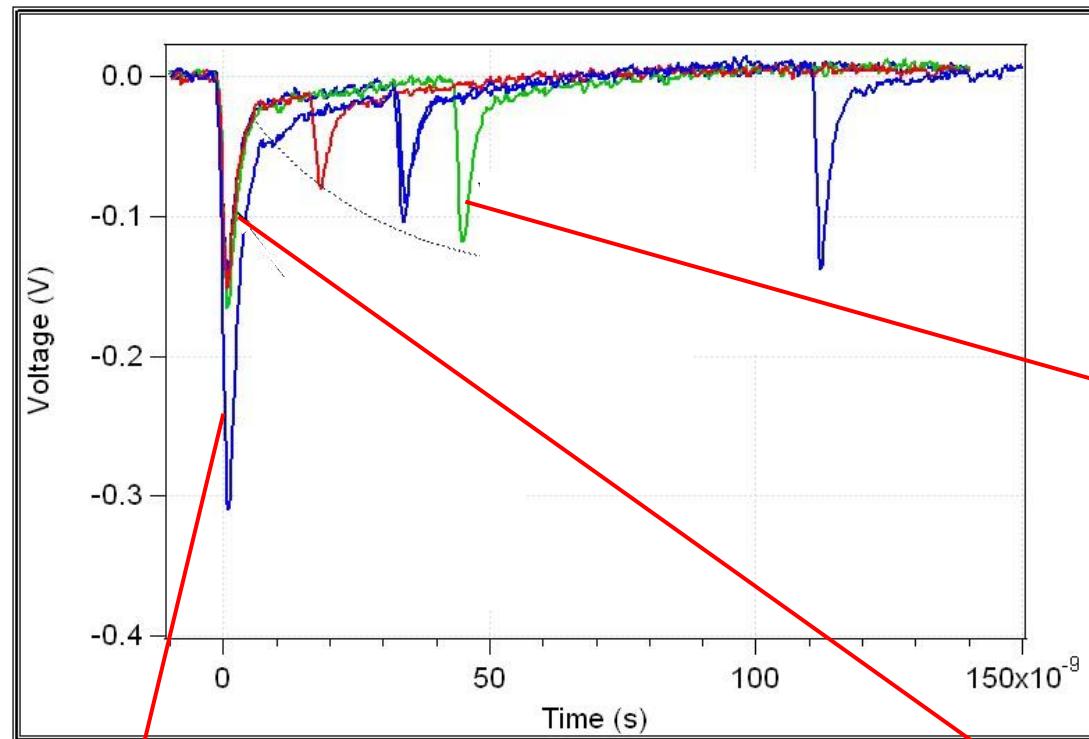
$$Gain = \frac{Q_{pixel}}{e} = \frac{C_{pixel} \times (Vbias - VBD)}{e}$$



$5 \times 10^4 < Gain < 4 \times 10^6$

# Other noise sources

Noise : pulses triggered by non-photo-generated carriers



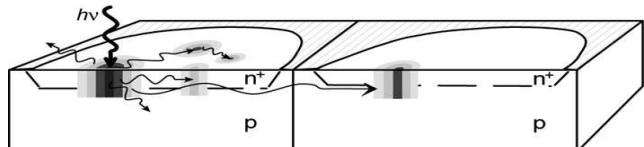
After-pulses

carriers trapped during the avalanche can produce delayed secondary pulses

Cross-talk

Dark noise

Thermally produced avalanche.  
Looks the same as pulse from photon

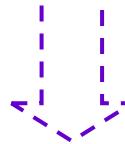


An avalanche in one pixel may produce an optical photon which can trigger another avalanche in a neighboring pixel without delay

# Ongoing studies on secondary effects and temperature dependence of SiPM

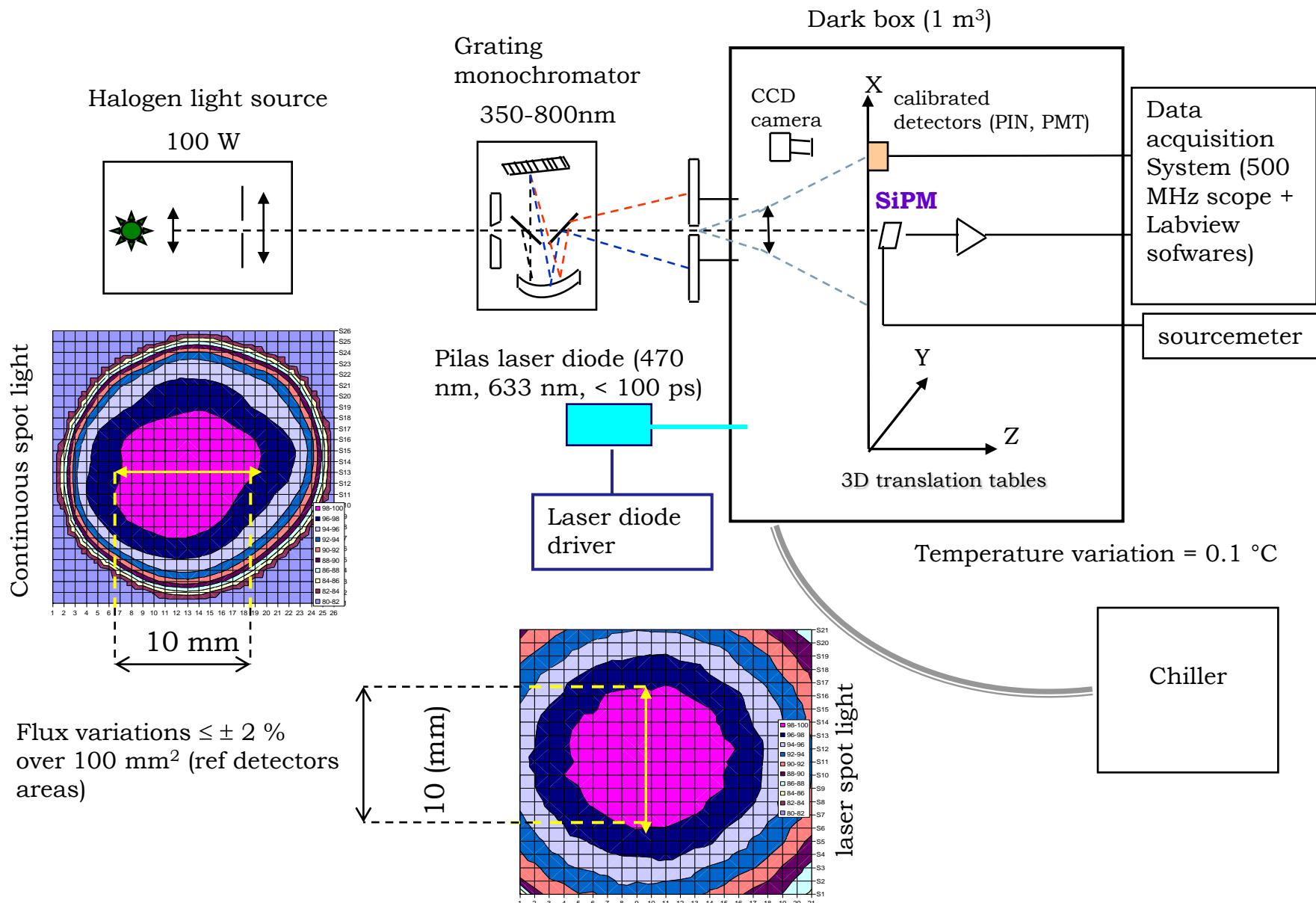


- ❖ After-pulses
  - ❖ Cross-talk
  - ❖ Temperature dependence of the  $V_{BD}$ , gains, DCR, pulse shape
- Off-line waveform analysis (collaboration with FERMILAB)  
→ calculation of the total gain



To be published soon

# Facility 2 : The Optical Test Bench



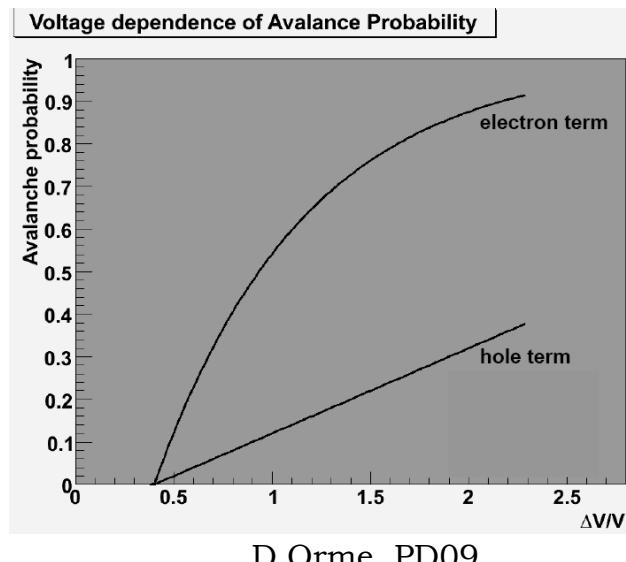
# Photon Detection Efficiency

$$PDE = Q_{\varepsilon} \times P_{trigg} \times \mathcal{E}_{geo}$$

Quantum efficiency  
→ function of incident photon wavelength

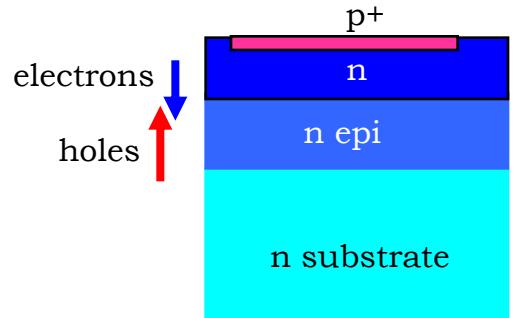
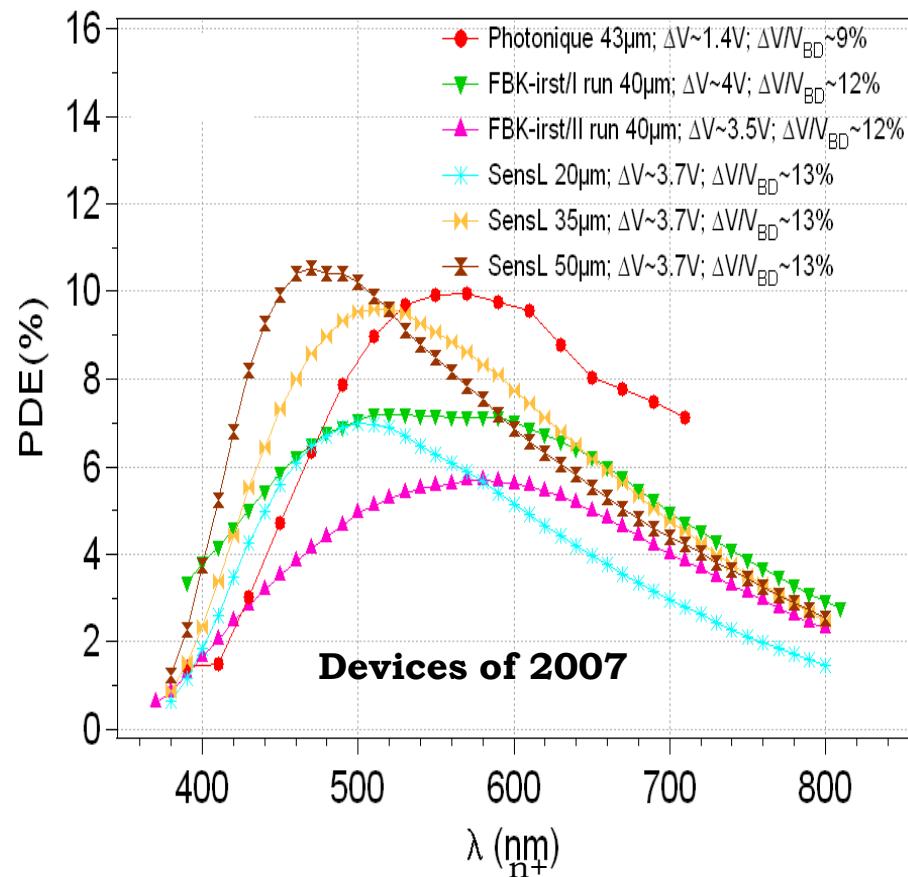
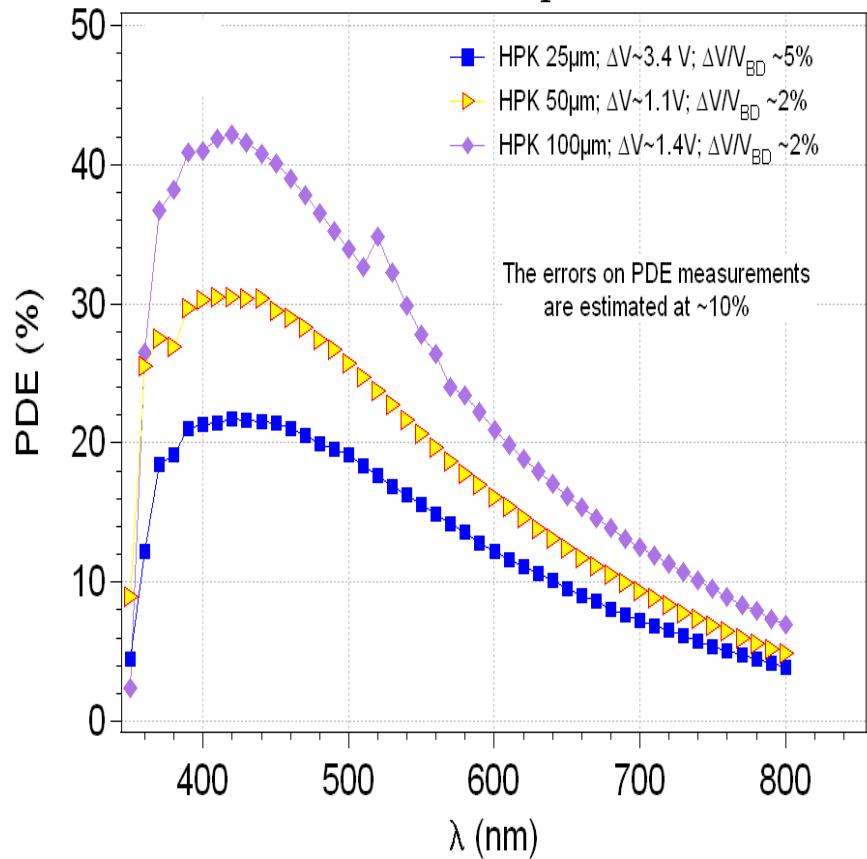
Avalanche triggering probability  
probability of photoelectron creating an avalanche → function of over-voltage

Geometrical fill factor :  
Sensitive/total area

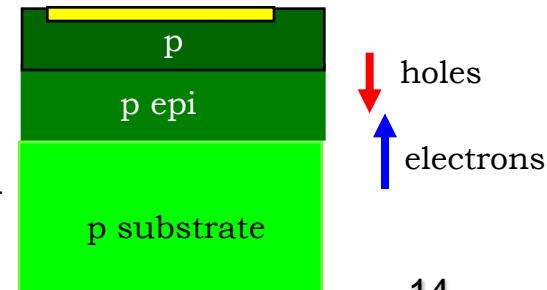


# Measurement of the Photon Detection Efficiency with continuous light at 25 °C (errors +/- 10 %)

After-pulses and cross-talk taken into account.



PDE shape is dependent of the structure:  
p-on-n is more blue sensitive than n-on-p(e- trigger avalanches at short  $\lambda$ )

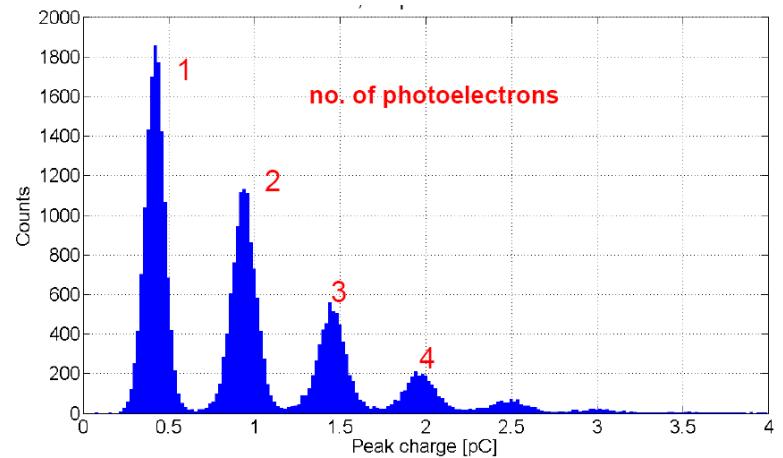


# More PDE measurements : work in progress

## Counting method : measurement with pulsed light

$$PDE_{counting} = \frac{(N_{light} - N_{dark})_{SiPM} \times A_{SiPM}}{(I_{light} - I_{dark})_{PMT}} \\ \times G_{PMT} \times \mathcal{E}_{Q_{PMT}} \times A_{PMT} \times q_e$$

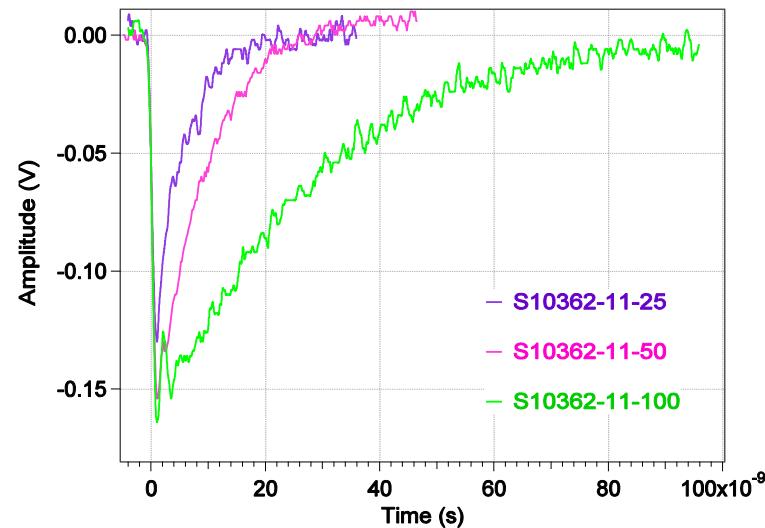
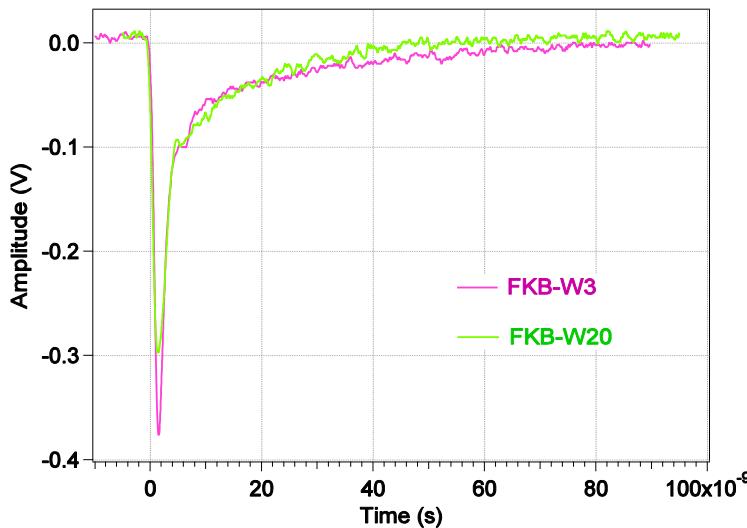
- no need to calculate the gain
- decrease of the errors on PDE



Comparison of the 2 methods → results to be published soon (maybe a poster at VCI 2010)

# SiPMs Timing Resolution measurements

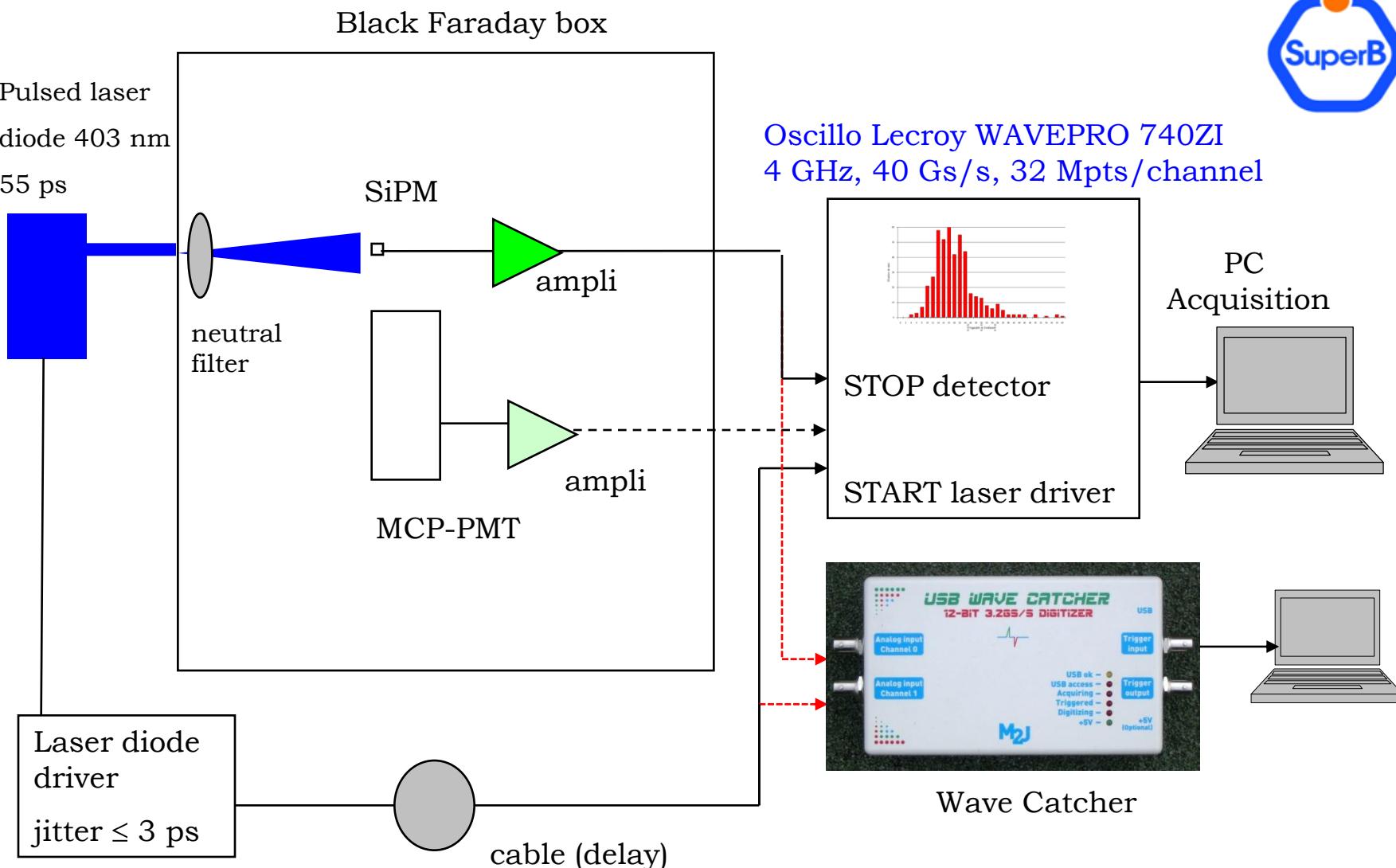
Pulse shapes of FBK SiPMs and HAMAMATSU MPPCs



## Goals of the study :

- ❖ Complete our characterization of SiPM with its timing properties
- ❖ Study the SiPM as a candidate for the TOF of the forward PID
- ❖ Give inputs for the whole detection chain simulation (LAL SuperB Physics group)
- ❖ Compare it with MCP-PMT
- ❖ Give “real” conditions for the tests of Wave Catcher (LAL electronics group)

# Timing Resolution test bench (to be built)

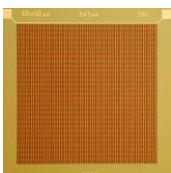


**INFN financing (2009) : 20 k€  
+ IN2P3 financing 2009) : 50 k€**

# New Photo-detectors to test (delivery in January)



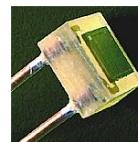
## F.B.K



1 mm<sup>2</sup> 400 pixels (50 µm)  
9 mm<sup>2</sup> 3600 pixels (50 µm)

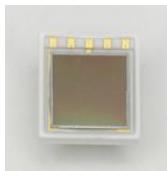
Samples given for evaluation

## Photonique



**SSPM-0710G9mm**  
9 mm<sup>2</sup> 8100 pixels

## HAMAMATSU



**S10362-33** 9 mm<sup>2</sup>  
14400 pixels (25 µm)  
3600 pixels (50 µm)  
900 pixels (100 µm)

## S10985-025C

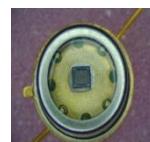
2 x 2 array (9 mm<sup>2</sup>) → 36 mm<sup>2</sup>

## 10-100S-FS 10-50S-B-4KS

New development « Wide trace »  
for a better timing resolution

Samples given for evaluation

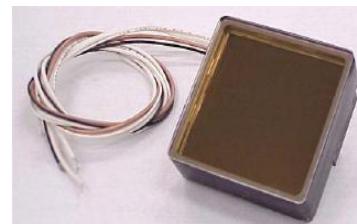
## Sensi



## SPMMicro 9 mm<sup>2</sup>

8640 pixels (20 µm)  
848 (35 µm)  
216 (50 µm)

## BURLE MCP-PMT 8512



25 µm pore, 8×8 array,  
53×53 mm active area

# Conclusion, further work



## Measurement of the SiPM timing resolution in function of the :

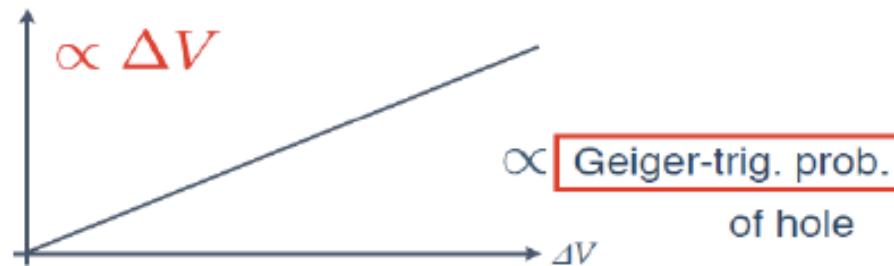
- ❖ over-voltage
- ❖ wavelength (403 nm and 633 nm)
- ❖ simultaneous incident number of photons
- ❖ light spot size and position
- ❖ temperature

## Comparison with Burle MCP-PMT

# Additional slides

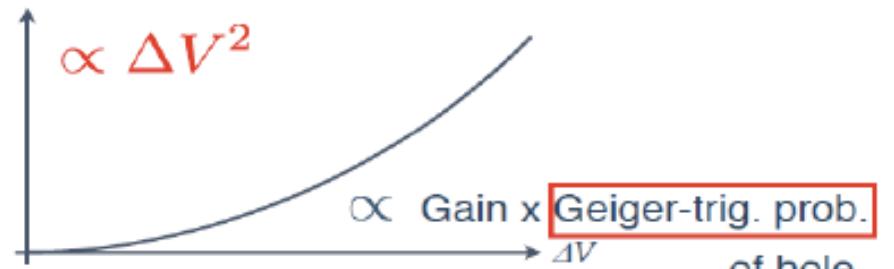
# T. Murase, PD09

## Random noise

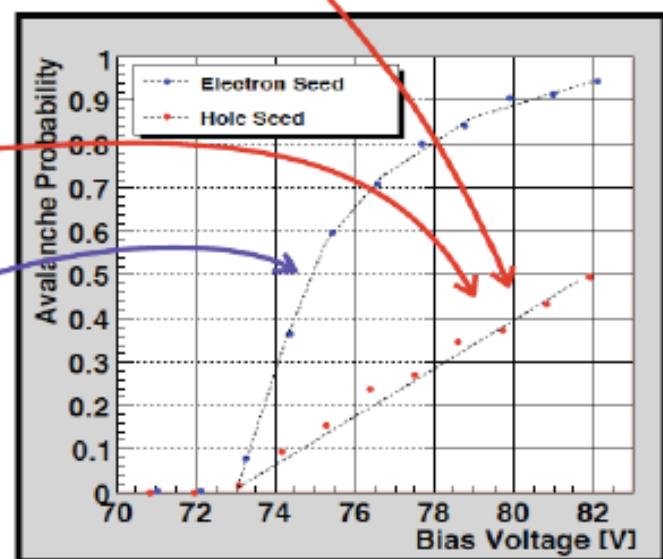


With considering the electric field structure and difference of impact ionization probability of e/h, we can explain the voltage dependence of random noise, afterpulse, and PDE.

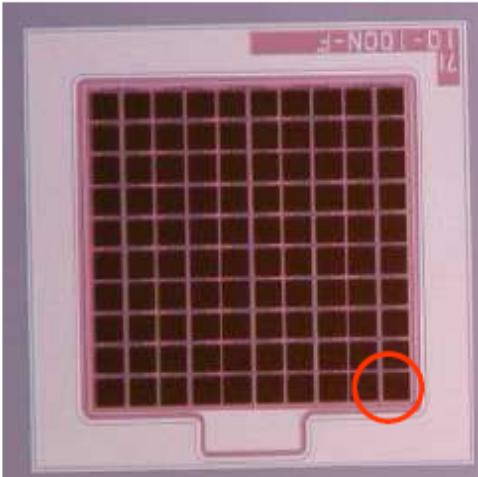
## Afterpulsing



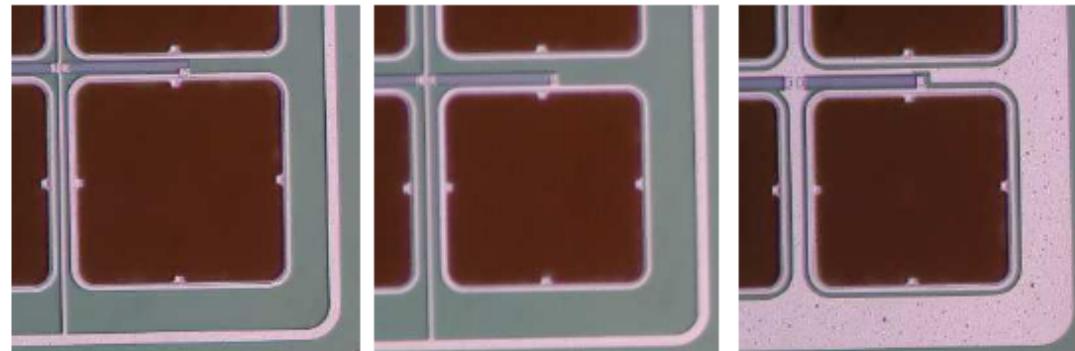
## Photon Detection Efficiency



# 100um pitch Samples



Quenching resistance =  $115\text{K}\Omega$  by forward IV curve



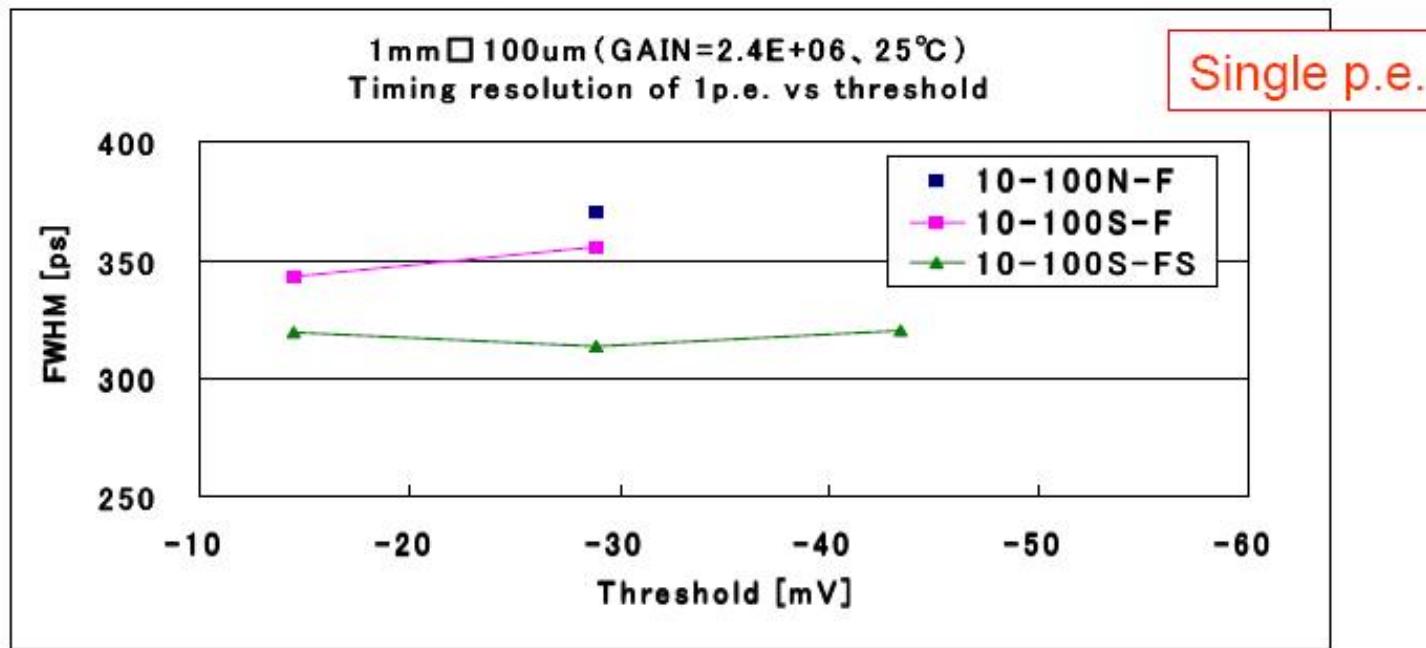
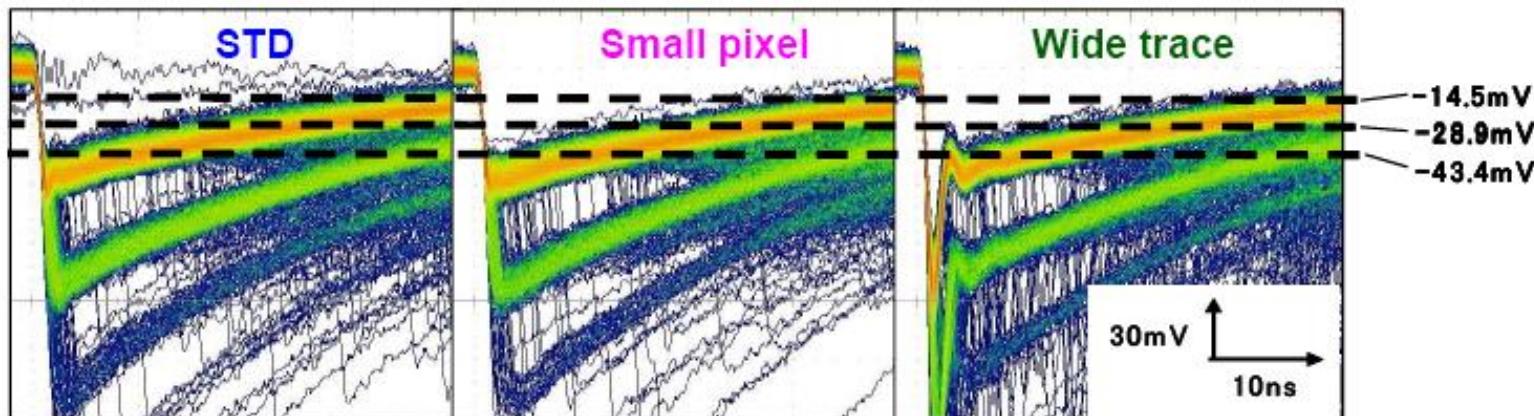
Sample name	10-100N-F ( STD )	10-100S-F ( Small pixel )	10-100S-FS ( Wide trace )
Fill factor	78 %	72 %	72 %
$\Delta V(V_{op} - V_{br})$ #1	1.02 V	1.18 V	1.18 V
Dark count at $V_{op}$	1075 Kcps	1089 Kcps	1243 Kcps
Pixel capacitance ( $C_d$ ) #2	373 fF	323 fF	325 fF
Stray capacitance / pixel #3	17 fF	37 fF	61 fF
PDE at $V_{op}$ , 440nm	79.7 %	76.2 %	77.6 %

#1 :  $V_{op}$  is at  $2.4\text{E}06$

#2 : by GAIN vs VR curve

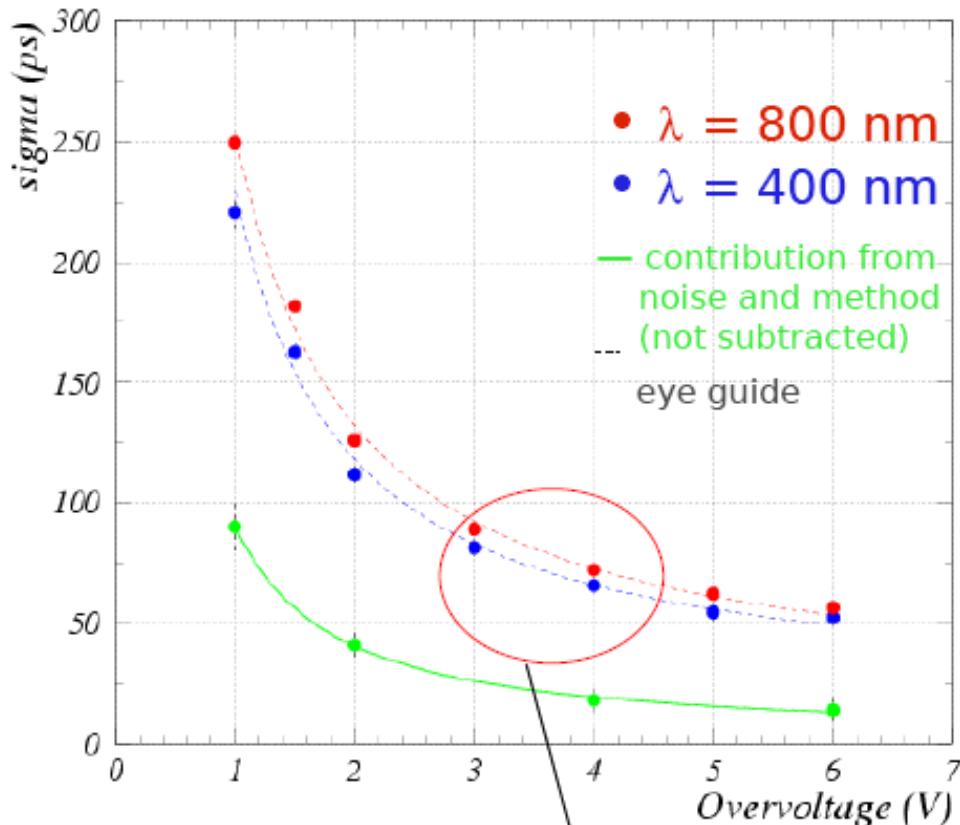
#3 :  $C_{total} / 100 - C_d$  at  $25^\circ\text{C}$

# Timing resolution of 100um pitch MPPCs



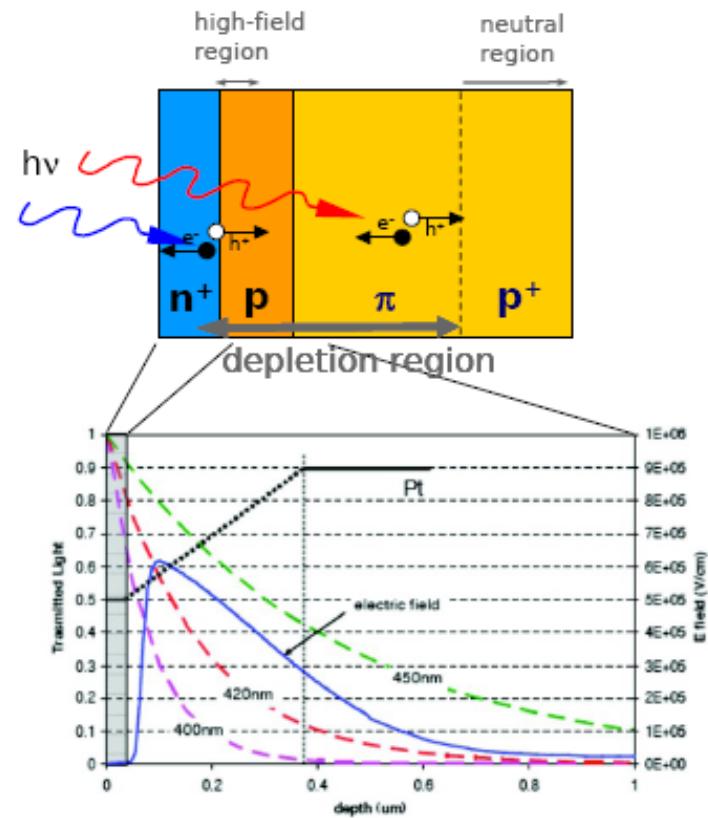
# Single photon timing

(FBK-IRST)

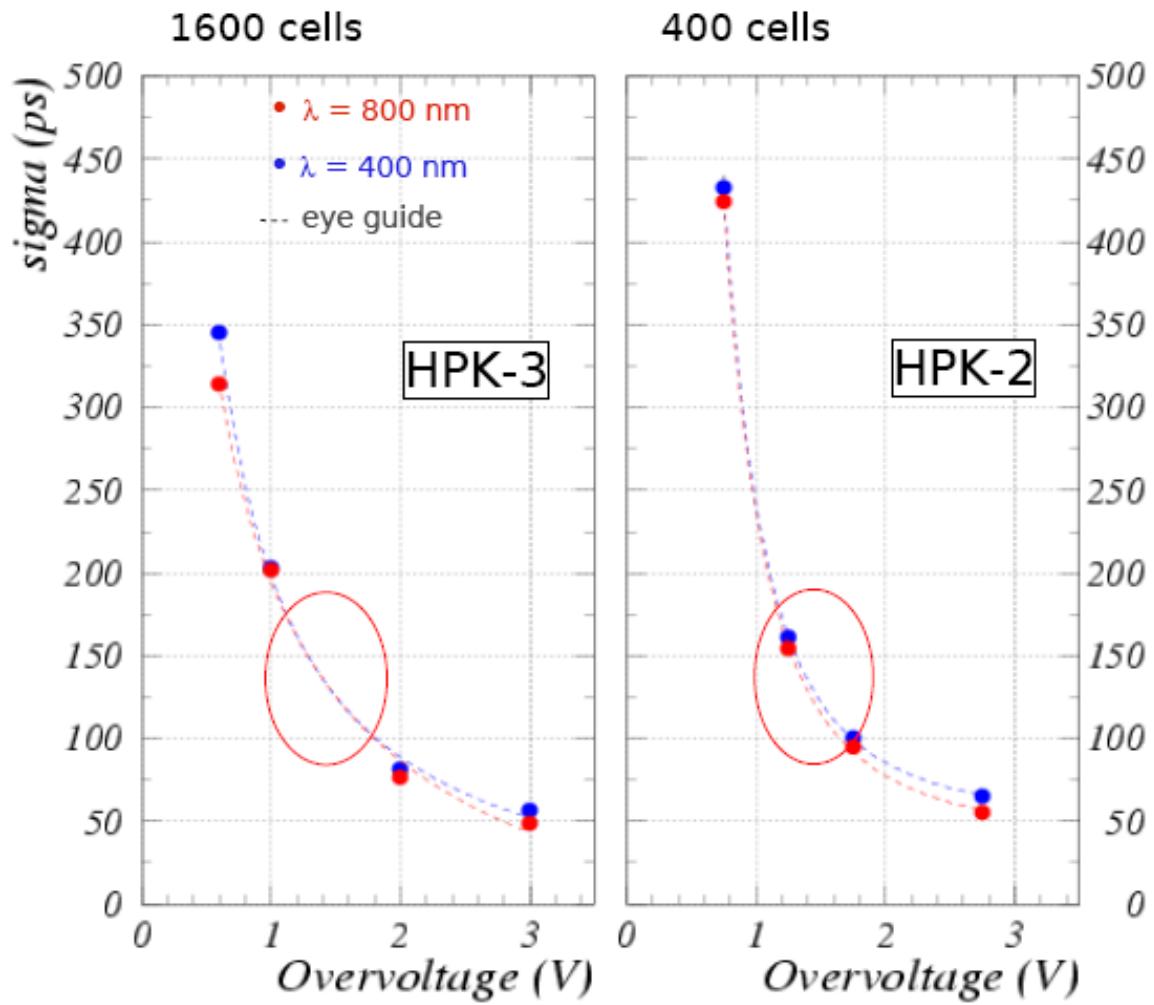


Typical working range

G.Collazuol et al.



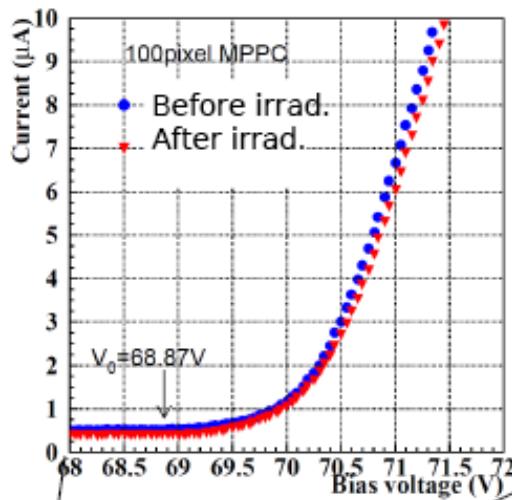
# Single photon timing (Hamamatsu)



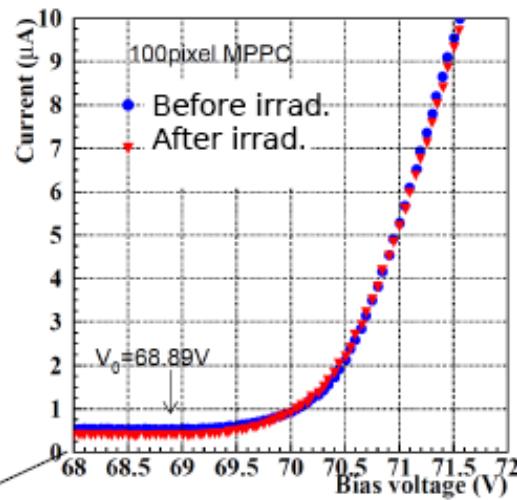
G.Collazuol (unpublished)

# Radiation damage: neutrons (0.1 -1 MeV)

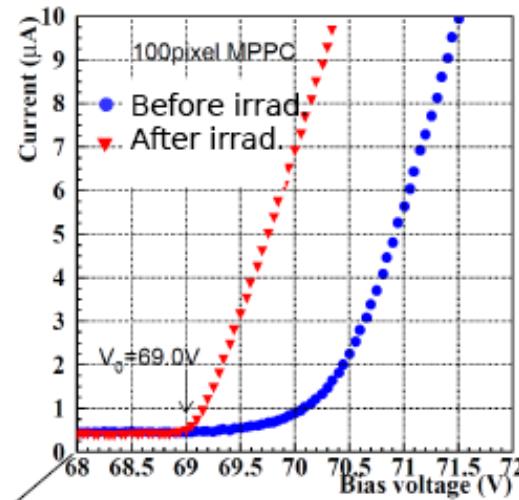
$8.3 \times 10^4 \text{ n/mm}^2$



$3.3 \times 10^5 \text{ n/mm}^2$



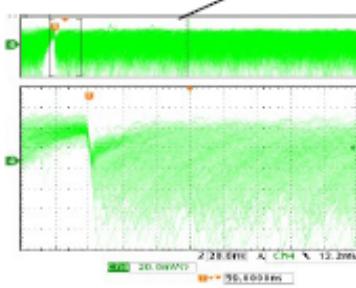
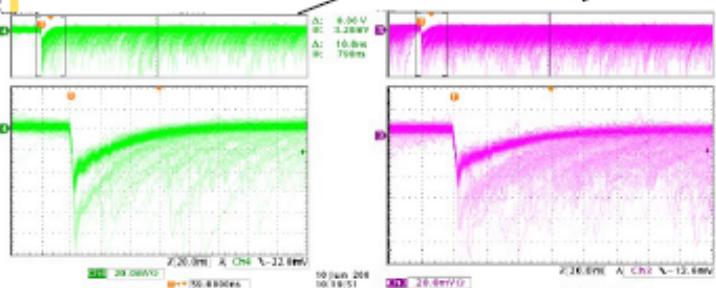
$1.0 \times 10^8 \text{ n/mm}^2$



$10^5 \text{ n/mm}^2$        $10^6 \text{ n/mm}^2$        $10^7 \text{ n/mm}^2$        $10^8 \text{ n/mm}^2$        $10^9 \text{ n/mm}^2$        $10^{10} \text{ n/mm}^2$

No significant change

Gianmaria Collazuol - ANIMMA 2009



I-V drastically change. No signal  
Signal pulse is still there,  
but continuous pulse height.  
(No photon-counting capability)

Nakamura at NDIP08

T.Matsumura - PD07